DEC 1 7 2003

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
	:	Examiner: Unassigned
SEIJI MISHIMA)	
	:	Group Art Unit: Unassigned
Application No.: 10/665,425)	
	:	
Filed: September 22, 2003)	
,	:	
For: METHOD FOR MANUFACTURING)	
AN ELECTRON SOURCE SUBSTRATE	:	December 17, 2003

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

<u>INFORMATION DISCLOSURE STATEMENT</u>

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. A copy of each of the listed documents is enclosed.

European Patent Application No. 0 869 528 and Japanese Patent Application

Laid-Open No. 10-334837 are discussed at page 5 of the specification and may be relevant for the reasons discussed therein.

European Patent Application No. 0 869 528 and U.S. Patent No. 6,144,154 are English-language counterparts to Japanese Patent Application Laid-Open No. 10-334837.

An abstract for Japanese Patent Application Laid-Open No. 10-334837, obtained from a commercial database, is enclosed for the Examiner's convenience.

FORMAL MATTERS

In accordance with 37 C.F.R. § 1.97(b), since this Information Disclosure

Statement is being filed within three months of the filing date of the subject application, neither a statement under 37 C.F.R. § 1.97(e) nor payment of a fee is required for consideration of this Information Disclosure Statement.

CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that an initialed copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our below-listed address.

Respectfully submitted,

Attorney for Applicant

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DWP/tmc

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LEG OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary) December 17, 2003		ATTY DOCKET NO. APPLICATION NO. 10/665,425 APPLICANT						
		SEIJI MISHIMA FILING DATE September 22, 2003		GROUP Unassigned				
U.S. PATENT DOCUMENTS								
INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE		
	6,144,154	11/2000	Yamazaki et al.					
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						· · · · · · · · · · · · · · · · · · ·		
	<u> </u>	FO	REIGN PATENT DOCUMENTS					
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT		
	EP 0 869 528	10/1998	ЕРО		_	In English		
	JP 10-334837	12/1998	Japan			Abstract*		
	·							
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)								
*Note: English-language counterpart documents also submitted (see text of IDS). EXAMINER DATE CONSIDERED								
EXAMINED: Initial if reference considered, whether or not citation is in conformance with MPER 600; Deau line though disting if not in conformance with MPER 600; Deau line though disting if not in conformance with MPER 600; Deau line though disting if not in conformance with MPER 600; Deau line though disting if not in conformance with MPER 600; Deau line though distinguished with the conformance with MPER 600; Deau line though distinguished with the conformance with MPER 600; Deau line though distinguished with the conformance with MPER 600; Deau line though distinguished with the conformance with MPER 600; Deau line though distinguished with the conformance with MPER 600; Deau line though distinguished with the conformance with MPER 600; Deau line though distinguished with the conformance with MPER 600; Deau line though distinguished with the conformance with MPER 600; Deau line though distinguished with the conformance with MPER 600; Deau line though distinguished with the conformance with MPER 600; Deau line though distinguished with the conformance with MPER 600; Deau line though distinguished with the conformance with MPER 600; Deau line though distinguished with the conformance wi								

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicants.

Sheet 1 of 1

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